



AIXTRON 1. Capital Markets Day

CMD 2018 Presentation 2
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GaN & SiC Power Electronics Market Drivers

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GaN & SiC Power Electronics Market Opportunities

Sources: EPC, Wolfspeed



Device

(50V)

- Satellite com, radar
- Telecom base-stations
- RF Power Amplifier for 5G
- Industrial heating

Application

(<200V)

- Wireless charging (AirFuel™ standard)
- Powering LiDAR systems
- DC-DC power conversion

(650V)

- Fast chargers for mobile devices
- Compact power supplies
- On-Board Charger EVs

Diode, MOSFET (650, 1.2-3kV)

- Solar Inverter
- On-Board Charger
- Main Power Inverter EVs
- Charging piles

Technology

GaN on Si

SiC on SiC

GaN on SiC

Advantages of SiC Power Electronics Systems



Early adopters:
SiC solar inverter & on-board chargers for
PHEV and EV

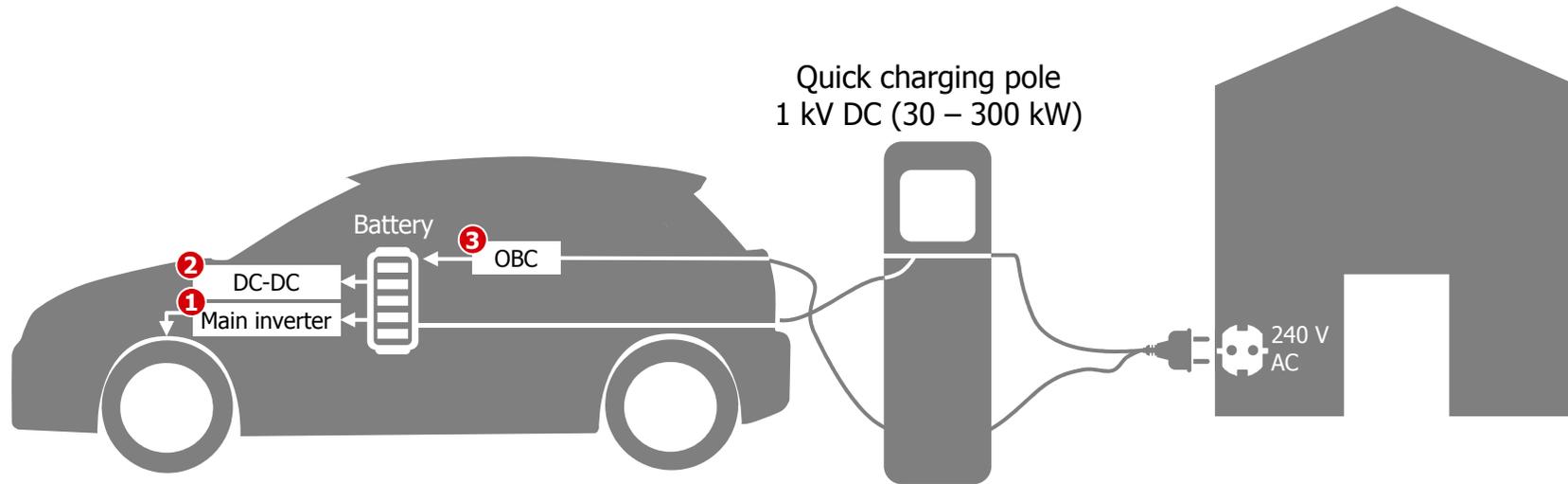
SiC power electronics systems compared to Si:

- **5x** lighter
- **3x** smaller
- **25%** lower semiconductor losses

Next big opportunity:

SiC power inverter in electric vehicles (EVs)

SiC Automotive Market Opportunity is based on the Main Inverter as this consumes > 80% of the wafer area



Component	Power (kW)	Fraction 6" wafer	
Main inverter	20 – 150	0,1 – 0,5	<div style="background-color: #008000; color: white; padding: 10px; border-radius: 10px;"> <p>Higher efficiency enables</p> <ul style="list-style-type: none"> ➤ Battery size reduction ➤ Cost savings ➤ Range extension </div>
DC-DC Converter	1 – 3	<0,01	
On Board Charger (OBC)	5 – 30	0,01	
(Quick) Charging Pole	30 – 300	0,1 – 1	

electronics
 Brings 240 V AC energy from wall plug to battery
 Brings 1–3 kV DC energy directly from grid to battery

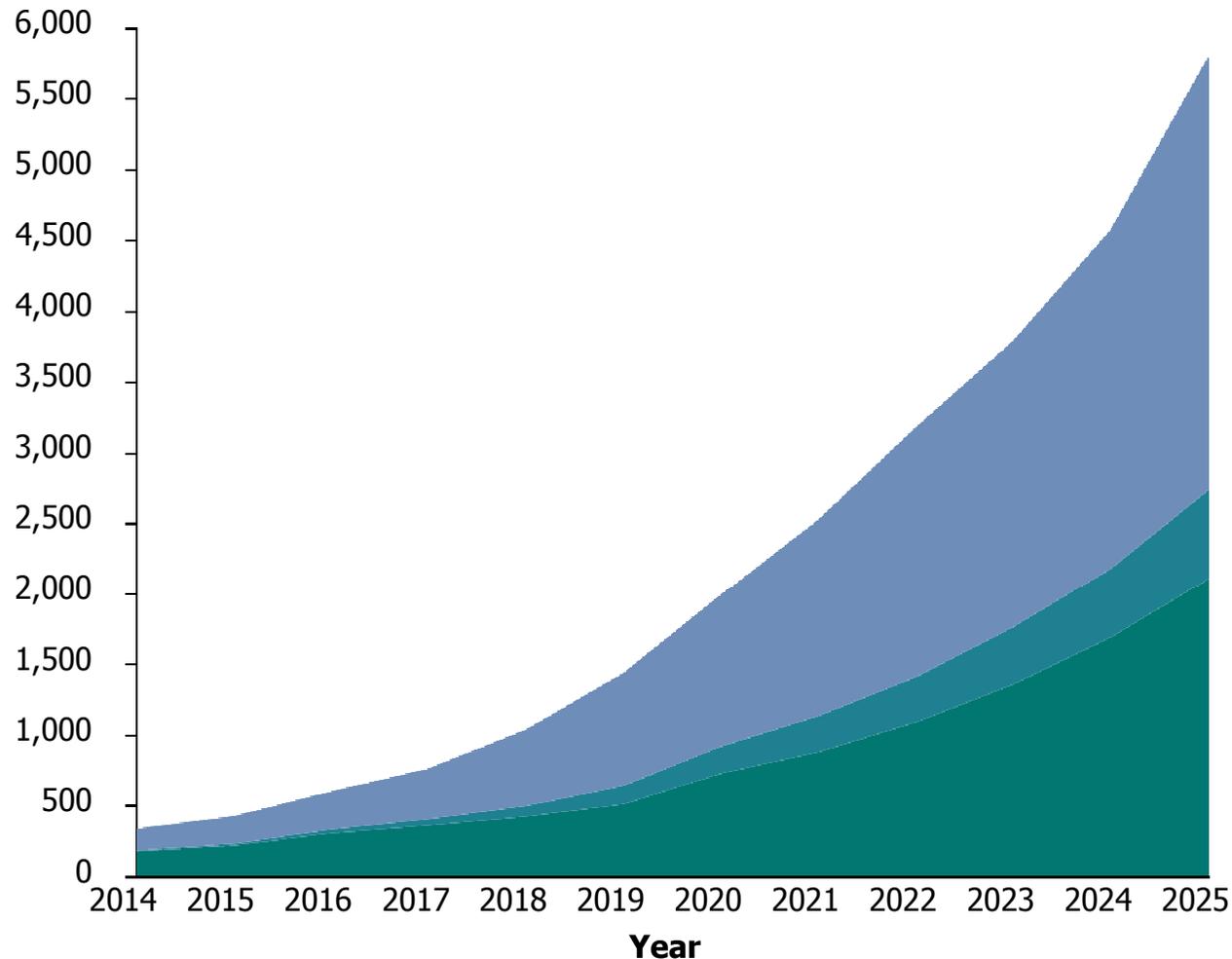
Rough order-of-magnitude estimates

GaN and SiC Device Market Forecast – SiC expected to be largest WBG Power Semiconductor Segment by 2025

Source: IHS 2016; YOLE 2017

IHS: GaN and SiC Semiconductor Device Forecast
YOLE: GaN RF Device Market
in USD Mio

■ SiC Device Forecast ■ GaN PE Device Forecast ■ GaN RF Device Forecast



- SiC is expected to be the largest Wide Bandgap Power Market, followed by GaN RF and GaN power
- Largest upside is in the SiC Market with Opportunities in the Electric Drive train of EVs

AIXTRON's (MO)VPE— Key Enabling Technology for GaN & SiC

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One Platform, two Material Systems, huge Market Opportunities

GaN

AIX G5+ C The Tool of Record for GaN on Si HVM



SiC

**AIX G5 WW
Batch Reactor Productivity with
Single Wafer Performance**

The Enabling Solution

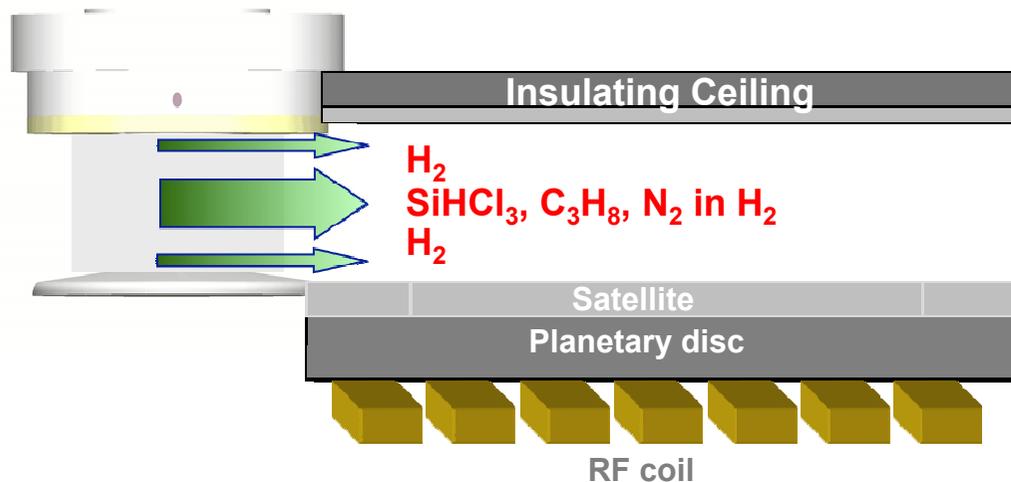
- **Wide Band-Gap Materials – Efficient Power Electronics Applications – Multi Billion Dollar Market Opportunity**
 - Multi-kW systems require large chip areas
 - Market needs HVM solution with high sensitivity to yield, cost and productivity
- **Requirements to (MO)VPE System**
 - Best Deposition Uniformity Control – at wafer level
 - Lowest Cost per wafer
 - High throughput
 - Low cost of consumables B



AIX G5 WW

Highest Yields on 150mm – The Planetary Reactor® Principle

Reactor Principle



SiC Epitaxy Requirements

Device class	Drift layer thickness
650V	6 μm
1200V	11 μm
1700V	16 μm
3.3kV	30 μm
6.5kV	60 μm
10kV	100 μm
15kV	150 μm

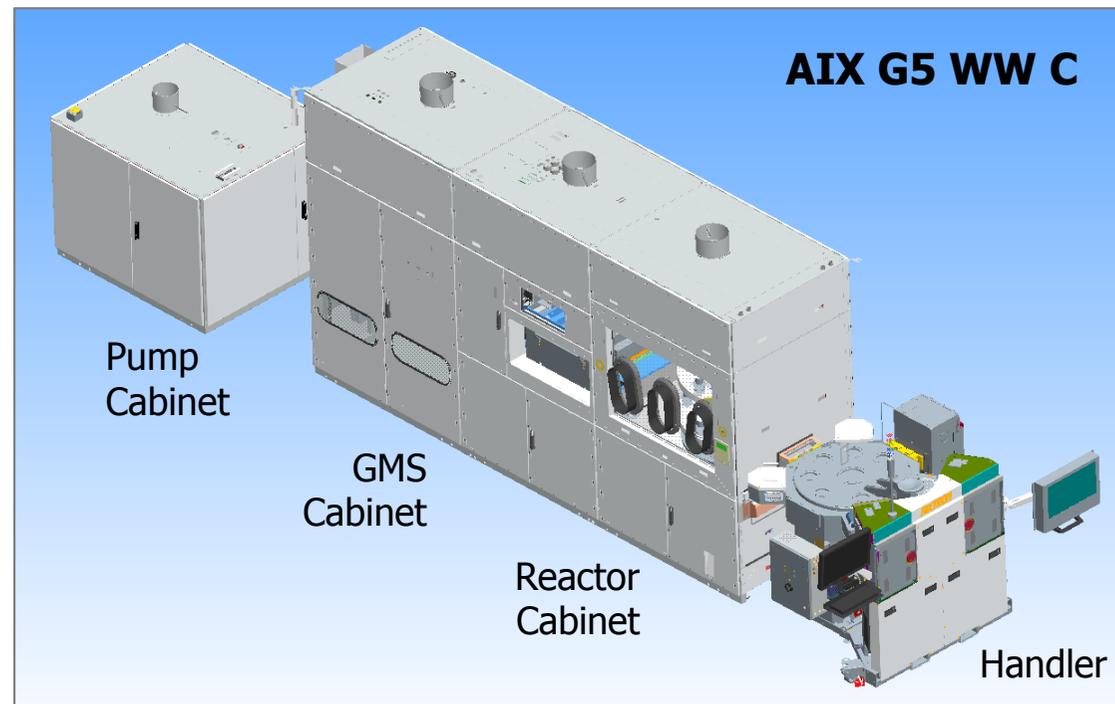
Different layer thickness for different products

Radial symmetric horizontal Planetary Reactor®

- Individual wafer rotation = best material uniformity
- Individual wafer temperature adjustment = wafer level control/correction
- Laminar flow reactor = wide process window
- High growth rate processes using TCS = high throughput

SiC - New Product with Automation increases Tool Throughput

- **Based on G5 WW 8x150 mm Planetary Reactor®**
- **Full Cassette-to-Cassette Wafer Automation (release to beta customers by Q4/18)**
- **Bay/Chase layout friendly**
- **Throughput gain enabled by hot loading/unloading of wafers**



GaN – AIXTRON is the Tool-of-Record for 150 & 200 mm



**G5+ C dual Planetary reactor module cluster
with
Cassette-to-Cassette wafer handling**

- **CSindustry awards 2016**
- **Fab integration** with 150 & 200 mm wafer cassette-to-cassette handler module
- **Best uniformities** thanks to Planetary concept
- **In-situ Reactor Cleaning** for AlGaN on Si process robustness and yield
- **On-wafer temperature process control** for highest reproducibility and yield

Development of next-gen product ongoing, timing not disclosed yet

Technology. Materials. Performance.

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